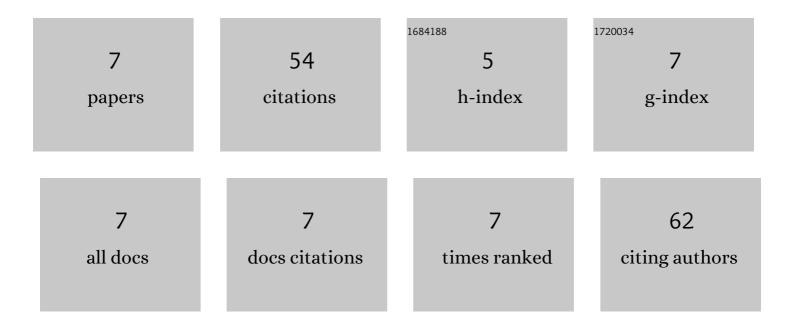
## **Matthias Schaller**

List of Publications by Year in descending order

Source: https://exaly.com/author-pdf/10627763/publications.pdf Version: 2024-02-01



#	Article	IF	CITATIONS
1	Chemical Repair of Plasma Damaged Porous Ultra Low-κ SiOCH Film Using a Vapor Phase Process. Journal of the Electrochemical Society, 2010, 157, H1140.	2.9	16
2	Investigation of physical and chemical property changes of ultra low-κ SiOCH in aspect of cleaning and chemical repair processes. Microelectronic Engineering, 2010, 87, 457-461.	2.4	9
3	Improved characterization of Fourier transform infrared spectra analysis for post-etched ultra-low-Î <sup>®</sup> SiOCH dielectric using chemometric methods. Journal of Vacuum Science & Technology B, 2009, 27, 521-526.	1.3	7
4	<i>k</i> -Restoring Processes at Carbon Depleted Ultralow- <i>k</i> Surfaces. Journal of Physical Chemistry A, 2011, 115, 8282-8287.	2.5	7
5	Surface Energy and Wetting Behaviour of Plasma Etched Porous SiCOH Surfaces and Plasma Etch Residue Cleaning Solutions. Solid State Phenomena, 2009, 145-146, 319-322.	0.3	6
6	Silylation of silicon bonded hydroxyl groups by silazanes and siloxanes containing an acetoxy group. N-trimethylsilylimidazole vs. dimethyldiacetoxysilane. Computational and Theoretical Chemistry, 2012, 991, 44-47.	2.5	5
7	How to evaluate surface free energies of dense and ultra low-κ dielectrics in pattern structures. Microelectronic Engineering, 2011, 88, 680-683.	2.4	4